NANOCHEM[®] Bulk Gas Purifier (MegaShield[™])

Features and Benefits

- For bulk and high flow specialty gas purification
- Highest Lifetimes
- Best Impurity Removal Efficiencies

 Removes critical contaminants to sub part-per-billion levels
- End-Point Detection available for many gases, at no extra charge.
- Enhances manufacturing process economy and improves equipment performance
- Provides consistently high purity gas, regardless of inlet impurity fluctuations
- Improves component lifetime and reduces particle generation by removing moisture from corrosive gases
- Easy to install & operate
- No heating or cooling required
- Quick start up
- Inlet and outlet isolation valves
- All metal parts, Type 316L stainless steel, or Nickel 200
- Mounting bracket
- Refills available for most gases (except toxic or corrosive gases)

Specifications

- 0.003 µm filter with 99.9999999% retention – Standard on MS-4000 and all ammonia purifiers
- Internal surface finish < 15 μ in Ra
- Maximum operating temperature is 70°C
- Maximum operating pressure is 150 psig (1.13 MPa) with endpoint detection;
 350 psig (3.51 MPa) without endpoint detection

Connections

• Female inlet and outlet connections, 1/2" VCR®-compatible face seal fittings

Options

- 0.003 µm filter with 99.9999999% retention available
- Three-valve manifold with isolation and bypass valves allows disconnection of purifier without interrupting process gas flow

Overview

NANOCHEM[®] MegaShield[™] Purifiers ensure gas consistency for bulk gas purification. Select MS-Series purifiers for flow rates up to 1000-1500 slpm (60-90 Nm³/hr). A variety of sizes are available to meet capacity and lifetime requirements. Seventeen (17) different purification media are available to purify over 70 gases.

MegaShield[™] (MS-Series)

MS-Series purifiers enable higher flow rates and lower pressure drops than the corresponding P-Series Models. MS-Series purifiers are available in 4, 8, 16, and 32 liter sizes. The purifier comes completely assembled, and consists of an inlet and outlet springless diaphragm valve; 2-4 canisters with suitable purification media, and a 100 μ m SS frit on the inlet and outlet.

MS-Series purifiers are completely retrofittable in P-Series installations. Media refills are available through MATHESON for all sizes.



Gas Type	Impurities Removed	
Nitrogen (N ₂), Argon (Ar),	< 100 ppt H ₂ O, O ₂ , CO ₂ LDL < 1 ppb CO*	
other inerts		
	< 100 ppt NMHC (with OMX-Plus™) LDL	
	$NO_{x'} SO_{x'} H_2 S$	
Ammonia (NH3)	< 100 ppt H_2O , O_2 , CO_2 in inert gas LDL	
	< 1 ppb CO*	
	< 45 ppb H ₂ O in ammonia LDL	
	NH ₃ -CO ₂ complexes, SiH ₄ , Siloxanes, GeH ₄ , H ₂ S	
Silane (SiH4)	< 100 ppt H ₂ O, O ₂ , CO ₂ LDL	
	< 1 ppb CO*	
	Chlorosilanes, disilane, siloxanes, arsine, phosphine	
Hydrogen (H_2), Methane CH_4),	< 100 ppt H_2O , O_2 , CO_2 LDL	
Ethane (C_2H_6), other HC	< 1 ppb CO*	
	$NO_{x'} SO_{x'} H_2S$	
Sulfur Hexafluoride (SF ₆),	< 100 ppt H_2O , O_2 , CO_2 in inert gas LDL	
Carbon Tetrafluoride (CF ₄),	< 10 ppb O_2 , H_2O in sulfur hexafluoride LDL	
other fluorocarbons		
Oxygen (O_2), Carbon Dioxide (CO_2),	< 10 ppb H ₂ O	
Nitrous Oxide (N ₂ O)		
Carbon Monoxide (CO)	Metal Carbonyls: Fe, Ni	
Corrosives	< 1 ppb H_2O in inert gas	
(HCI, HBr, CI ₂ , SiH ₂ CI ₂ , SiHCI ₃ , BCI ₃)	$< 100 \text{ ppb H}_2\text{O} \text{ in HBr}$ LDL	
	$< 150 \text{ ppb H}_2\text{O}$ in HCl	
	Volatile Metals: Fe, Mo, Cr, Ni, Mn, Ti	

LDL – Lower Detection Limit by State-of-the-Art Analytical Instrumentation

NMHC – Non-methane Hydrocarbons

*NOTE: CO is removed efficiently by OMX & OMX-Plus[™] media at low flow rates (recommend 1/10 of normal flow rate)

For a detailed list of purification media and impurities removed, refer to the Purification Media Table in Nanochem® Purification Solutions Brochure.





NANOCHEM[®] MegaShield[™] Gas Purifiers

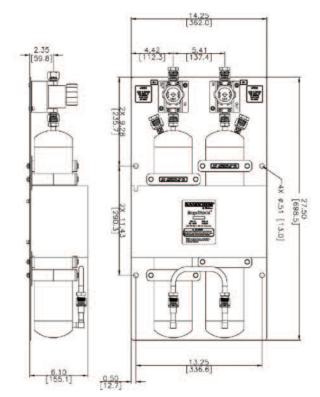
	Model	
Specifications	MS-4000 / 8000	MS-16000 / 32000
Max flow rate, slpm (NM ³ /hr) of N_2 *	1000 (60) *	
Max Pressure, psig (MPa) **	350 (2.51)	
Purification medium bed volume, Liters	4, 8	16, 32
Wetted Parts	316L SS, Nickel 200 gaskets,	
	PCTFE & TFE valve components	
Connection Type	1/2" Female VCR®-compatible face-seal fittings	
Standard outlet filter	100 µm frit	
Optional filter***	0.003 µm; 9-log retention	
Flow Rate w/ optional filter, slpm N_2 *	1000	
Dimensions, inches (mm)		
A - Width of purifier mounting plate	14.25 (361.95)	14.25 (361.95)
B - Depth of purifier	7.00 (177.8)	11.29 (286.77)
C - Height of purifier mounting plate	27.5 (69.85)	49.38 (1254.25)
D - In/Out center line to mounting plate	2.35 (59.69)	3.38 (85.73)
E - Mounting plate top to in / out connection	0.45 (11.43)	0.45 (11.43)
F - Distance between bolt holes	13.25 (336.55)	13.25 (336.55)
G - Distance between in / out connections	5.41 (137.41)	5.41 (137.41)
H - Distance between plate top & bolt hole	9.28 (235.71)	9.73 (247.14)
I - Bolt hole diameter	Ø 0.50 (12.70)	Ø 0.50 (12.70)

NOTE: The maximum specified flow rate is based upon a 10 psi (0.07 MPa) pressure drop.

Flow rates up to 1500 slpm (90 NM₃/hr) can be attained with the MS-Series, if higher pressure drops are acceptable

** Maximum operating pressure is 150 psi (1.13 MPa) when the endpoint detector is installed.

*** 0.003 µm filter standard on MS-4000

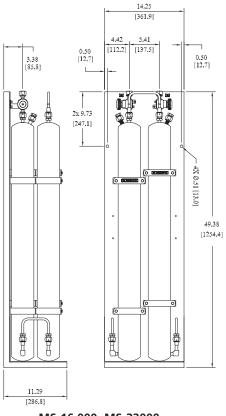


MS-4000, MS-8000 (shown)

Equipment Technology Center

166 Keystone Drive Montgomeryville, PA 18936 Tel: 800-828-4313 • Fax: 215-619-0458 Email: Info@mathesongas.com

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MS-16,000, MS-32000

